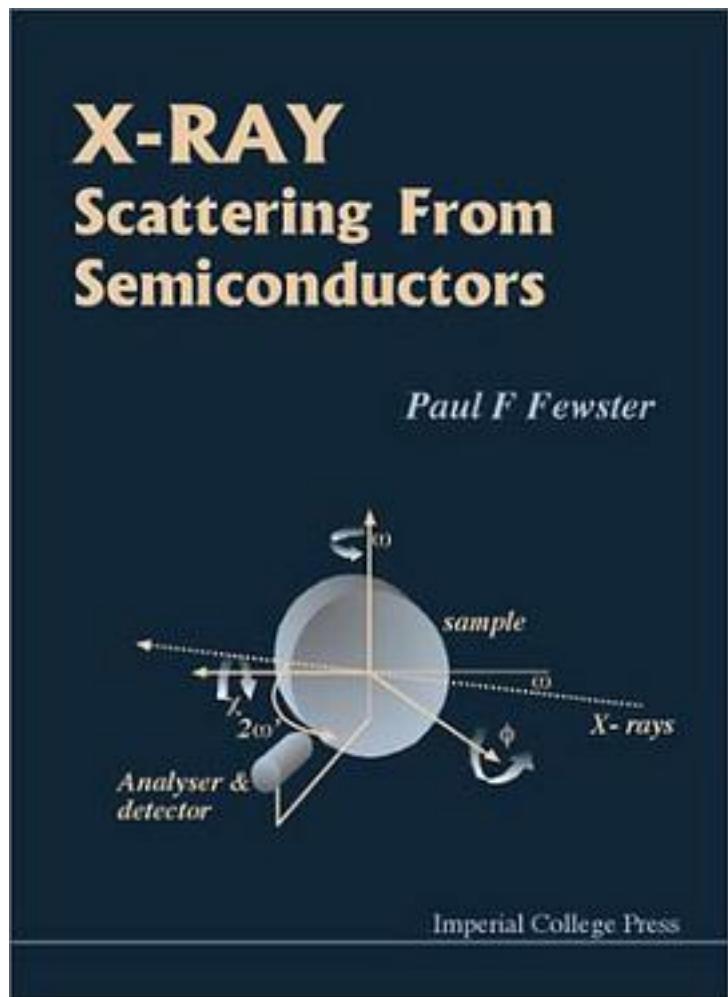


# X-Ray Scattering from Semiconductors



[X-Ray Scattering from Semiconductors\\_下载链接1](#)

著者: Fewster, Paul F.

出版者:

出版时间: 2001-2

装帧:

isbn: 9781860941597

X-ray scattering is used extensively to provide detailed structural information about materials. Semiconductors have benefited from X-ray scattering techniques as an

essential feedback method for crystal growth, including compositional and thickness determination of thin layers. The methods have been developed to reveal very detailed structural information concerning material quality, interface structure, relaxation, defects, surface damage, and more. This text provides a description of the techniques involved in obtaining that information, including X-ray diffractometers and their associated instrument functions, data collection methods, and the simulation of the diffraction patterns observed. Also presented are examples and procedures for interpreting the data to build a picture of the sample, much of which is common to materials other than semiconductors.

作者介绍:

目录:

[X-Ray Scattering from Semiconductors 下载链接1](#)

标签

评论

suitable for researchers in semiconductor materials/thin films

---

[X-Ray Scattering from Semiconductors 下载链接1](#)

书评

---

[X-Ray Scattering from Semiconductors 下载链接1](#)